



2623
#8

PATENT
Customer No. 22,852
Attorney Docket No. 04329.2409

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Kei YOSHIKAWA et al.) Group Art Unit: 2623
)
Application No.: 09/662,219) Examiner: S. Ahmed
)
Filed: September 14, 2000)
)
For: PATTERN CORRECTING)
METHOD OF MASK FOR)
MANUFACTURING A)
SEMICONDUCTOR DEVICE AND)
RECORDING MEDIUM HAVING)
RECORDED ITS PATTERN)
CORRECTING METHOD)

RECEIVED

FEB 18 2004

Technology Center 2600

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Reply to Interview Summary

In response to the Interview Summary dated January 29, 2004, Applicants respectfully submit that Claims 15-17, 19-23, 25-31, and 34-42 correspond to Species I. In view of the foregoing remarks, Applicants respectfully request the reconsideration and reexamination of this application and the timely allowance of the pending claims.

FINNEGAN
HENDERSON
FARABOW
GARRETT &
DUNNER LLP

1300 I Street, NW
Washington, DC 20005
202.408.4000
Fax 202.408.4400
www.finnegan.com

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: February 13, 2004

By: 

D. Kent Stier
Reg. No. 50,640
(404) 653-6559

FINNEGAN
HENDERSON
FARABOW
GARRETT &
DUNNER LLP

1300 I Street, NW
Washington, DC 20005
202.408.4000
Fax 202.408.4400
www.finnegan.com